

プロセス部



ナノ・スピニ実験施設クリーンルーム
(Clean room in Laboratory for
Nanoelectronics and Spintronics)

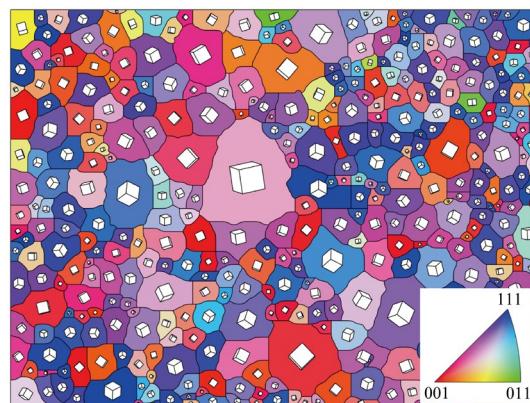


電子線描画装置
(Electron beam lithography system)

評価部



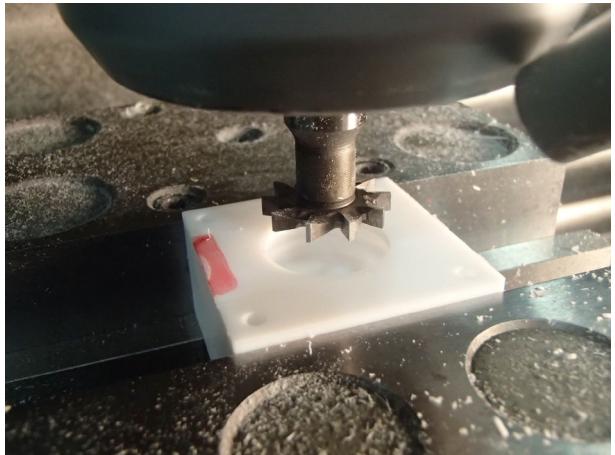
X線回折装置
(X-ray Diffractometer)



結晶方位の測定例
(Example of Crystal
Orientation Measurement)



走査型電子顕微鏡
(Scanning Electron Microscope)



テフロン樹脂の切削加工
(Teflon Resin Machining)

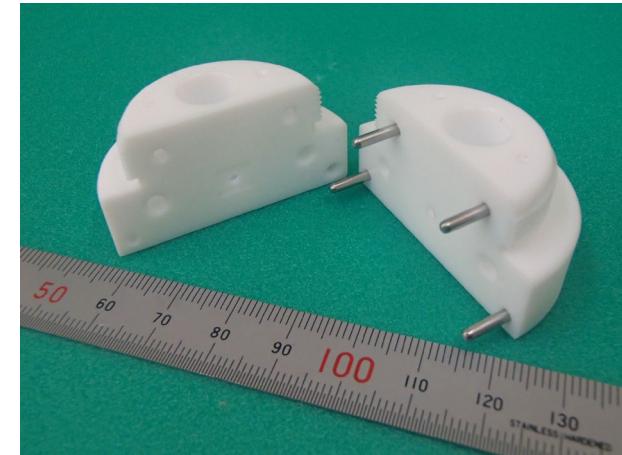
工作部



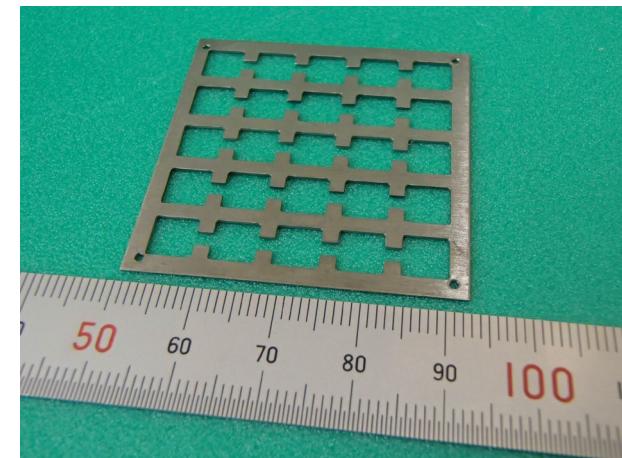
真空容器の加工
(Vacuum Chamber Processing)



附属工場内観
(Interior View of Factory)



テフロン樹脂製容器
(Teflon Resin Chamber)



タンタル製サンプルホルダー
(Tantalum Sample Holder)